

**SYSTEM AND METHOD FOR PROCESS CONTAMINATION PREVENTION
FOR SEMICONDUCTOR MANUFACTURING**

ABSTRACT

[0047] Provided are a system and method for preventing contamination in a semiconductor manufacturing environment. The method includes comparing one or more attributes associated with a product, such as a substrate, with one or more attributes associated with an operation. If the comparison indicates that the product is not compatible with the operation, then the operation is suspended with respect to the product. If the comparison indicates that the product is compatible with the operation, then the operation is performed on the product.